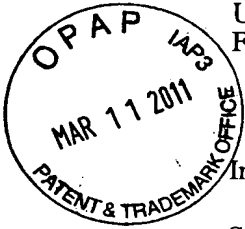


Docket No. F06-436-US
U.S. Serial No. 10/569,833
FUJIT.083

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent application of: Mineo HIRAMATSU, et al.

Serial No.: 10/569,838

Group Art Unit: 1715

Filing Date: December 6, 2006

Examiner: Louie, Mandy C

For: METHOD FOR PRODUCING CARBON NANOWALLS, CARBON NANOWALL,
AND APPARATUS FOR PRODUCING CARBON NANOWALLS

Honorable Commissioner for Patents
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

Under the provisions of 37 CFR §1.97 through §1.98 and pursuant to applicant's duty of disclosure under 37 CFR §1.56, applicant respectfully brings the following documents cited in Japanese Office Actions dated September 21, 2010, December 14, 2010 and December 21, 2010 in counterpart foreign applications and listed on the attached form PTO-1449, to the attention of the Examiner in charge of the above-identified application. Copies of the listed documents are provided herewith for the convenience of the Examiner (with English abstracts). Further, partial English language translations of the related sections of the Japanese Office Action are attached.

In compliance with the requirements of 37 CFR §1.98(a)(3), as a concise statement of relevance, as it is presently understood by the individual designated in 35 U.S.C. §1.56(c) most knowledgeable about the content of the information, the undersigned attorney of record submits a translation of portions of an official action by a foreign examiner in which the references were cited. The relevance to the pending U.S. patent application is that the references were cited in a foreign patent application on the same subject matter. However, no independent analysis of the reference, the accuracy of the statement of the foreign examiner or the claims of the foreign application under the laws of that country or the United States relative to the subject matter claimed in the present application has been made, the present understanding of the contents thereof by the undersigned being based on the translation of the foreign examiner's comments submitted herewith.

Docket No. F06-436-US
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This citation does not constitute an admission that the references are relevant or material to the claims. They are only cited as constituting related art of which the applicant is aware.

It is respectfully requested that the listed references be considered by the Examiner and formally made of record in this application.

Please charge any deficiencies in fees and credit any overpayment of fees to Attorney's Deposit Account No. 50-0481.

Respectfully submitted,

Date: 3/11/11

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